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Bending-strain-induced localized density of states in amorphous indium-gallium-zinc-oxide thin-film transistors

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Abstract

In this study, we examine the electrical characteristics of amorphous indium-galliumzinc-oxide (a-IGZO) thin-film transistors (TFTs) under bending strains by TCAD and SPICE simulations. Bending strains induce modifications of the localized density of states (DOS) in a-IGZO channel materials, which, in turn, cause changes in the electrical characteristics of the TFTs. The bending-strain-induced localized DOS, the above-threshold current, subthreshold current, and field-effect mobility are analyzed with the calibration of the current-versus-voltage curves of a reference device by TCAD simulation. Moreover, the device parameters that affect the device performance in SPICE simulation are calibrated to aid in SPICE modeling of the strained oxide TFTs.

Keywords- a-IGZO TFT, Bending strain, Flexible display, TCAD simulation

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